

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. : To Be Assigned Confirmation No. :  
Applicant : Toshio GOTO, et al.  
Filed : Concurrent Herewith  
TC/A.U. :  
Examiner :  
Docket No. : 101250.55460US  
Customer No. : 23911  
Title : Processing Apparatus

**INFORMATION DISCLOSURE STATEMENT  
UNDER 37 CFR §§ 1.97 and 1.98**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In accordance with the duty of disclosure under 37 CFR §1.56, Applicants hereby notify the U.S. Patent and Trademark Office of the documents which are listed on the attached Form PTO-1449 and/or listed herein and which the Examiner may deem relevant to patentability of the claims of the above-identified application.

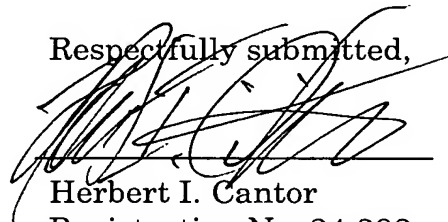
English abstracts summarizing the disclosures of the Japanese publications are submitted herewith.

The present Information Disclosure Statement is being filed (1) no later than three months from the application's filing date or (2) before the mailing date of the first Office Action on the merits (whichever is later), and therefore no certification under 37 C.F.R. §1.97(e) or fee under 37 C.F.R. §1.17(p) is required.

The submission of the listed documents is not intended as an admission that any such document constitutes prior art against the claims of the present application. Applicant does not waive any right to take any action that would be appropriate to antedate or otherwise remove any listed document as a competent reference against the claims of the present application.

If necessary, the paper should be considered as a petition for consideration of the Information Disclosure Statement under 37 C.F.R. §1.97(d)(2) and that the petition fee set forth in 37 C.F.R. §1.17(i) in accordance with 37 C.F.R. §1.97(d)(3) should be charged to Deposit Account No. 05-1323 (Docket # 101250.55460US).

Respectfully submitted,



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September 29, 2004

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DT04 PCT/PTO 29 SEP 2004

Substitute for form 1449A&B/PTO <b>INFORMATION DISCLOSURE          STATEMENT BY APPLICANT</b> <i>(use as many sheets as necessary)</i>				<i>Complete if Known</i>	
				Application Number	10/509656
				Filing Date	
				First Named Inventor	Toshio Goto
				Art Unit	
				Examiner Name	
Sheet	1	of	1	Attorney Docket Number	

## U.S. PATENT DOCUMENT

Examiner Initials*	Cite No. <sup>1</sup>	Document Number		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
		Number	Kind Code <sup>2</sup> (if known)		
		US			
		US			
		US			

## FOREIGN PATENT DOCUMENT

Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document			Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Translation <sup>6</sup>
		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> (if known)			
		JP	06-293960	A	10-21-1994	MATSUSHITA ELECTRIC IND CO LTD	Abstract
		JP	3162623	B	02-23-2001	TOKYO ELECTRON LTD	Abstract
		JP	04-053947	B	08-28-1992	NIPPON STEEL CORP	Abstract
		JP	04-081132	B	12-22-1992	HOKAIDO UNIV	Abstract
		JP	10-083893	A	03-31-1998	SONY CORP	Abstract
		JP	62-054871	B	11-17-1987	AGENCY OF IND SCIENCE & TECHNOL	Abstract

## OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation <sup>6</sup>
		Kono et al., "Plasma Absorption Spectroscopy Using Microdischarge Light Source" (May 2000)	Abstract
		Ohta et al, "Behaviors of Si, SiF, SiF <sub>2</sub> radicals and SiF <sub>4</sub> molecule in RF60MHz capacitively coupled SiF <sub>4</sub> plasma", Proceedings of International Symposium on Dry Process, The Institute of Electrical Engineer of Japan, October 10 - 11, 2002	Abstract
		Ohta et al., "The effect of driving frequency on the behavior of Si atoms in capacitively coupled VHF SiF <sub>4</sub> plasma", Proceedings of the 20 <sup>th</sup> Symposium on Plasma Processing, Division of Plasma Electronics, The Japan Society of Applied Physics, January 29 - 31, 2003	Abstract

Examiner Signature		Date Considered	
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>1</sup> Applicant's unique citation designation number (optional). <sup>2</sup> See Kinds Codes of USPTO Patent Documents at [www.uspto.gov](http://www.uspto.gov), MPEP901.04 or in the comment box of this document. <sup>3</sup> Enter office that issued the document, by the two-letter code (WIPO Standard ST.3) <sup>4</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup> Applicant is to indicate here if English language Translation is attached.